

CLAIMS

1. A microfluidic device, comprising
a substrate;
5 a plurality of resin layers formed on the substrate; and
a three-dimensional fluid circuit formed in the plurality of the resin layers.
2. A method of manufacturing a microfluidic device, comprising the steps of:
(a) forming a resin layer on a substrate, and forming a groove having a
10 predetermined pattern which functions as a fluid flow path by removing the resin
layer by laser processing;
(b) forming a subsequent resin layer by coating a resin on the overall
surface of the resin layer having been processed, and forming a groove and/or a
throughhole to the groove formed in the resin layer coated with the resin, by laser
15 processing of the subsequent resin layer;
(c) repeating the step (b); and
(d) forming a three-dimensional fluid circuit by finally forming inlets and
an outlet by resin coating.
- 20 3. The method of manufacturing the microfluidic device according to Claim 2,
wherein the resin is formed by a lamination method.
4. The method of manufacturing the microfluidic device according to Claim 2,
wherein the resin layer is formed by a spin coat method.